# **Glass Chips**

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## Hard Lithography (the good)

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- Indestructible
- Multiple coating types
- Electrical contacts are straight forward
- Small channels
- High repeatability
- Multiple on-chip components are

available (valves, pumps, mixers, etc.)

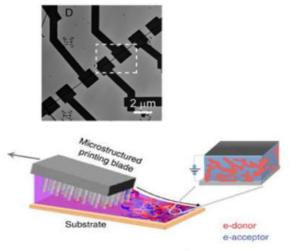
## Hard Lithography (the bad)

Expensive?
Consider labor costs
Consider detector costs

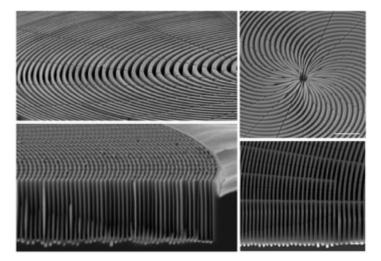
Long turn around time
We need 10's not millions
Most labs not done on-site
NanoX

## What is Nano-X ?

Nano-X is a 3100 sq. ft. class 100/10000 facility housing an advanced electron beam lithography tool and associated processing and metrology equipment. The toolset is aimed towards providing SLAC's scientific community with rapid nano-prototyping capabilities complementary to that of the current campus facilities.



On-chip in-situ and in-operando platforms for interface chemistry, advanced spectroscopy, theory-guided materials and nanosystems fabrication,



Optics for spatial and temporal control of x-rays, injectors, collimators, beam metrology

Nano-X is proposed to operate as a semishared facility with a percentage of time allocated for usage by trained personnel from the broad SLAC/Stanford community. Compared to the campus facilities, the equipment toolset will have a higher degree of oversight, quality control, and stability and a more rigorous training requirement.

### Slide materials courtesy of Anne Sakdinawat

## Why Nano-X at SLAC?

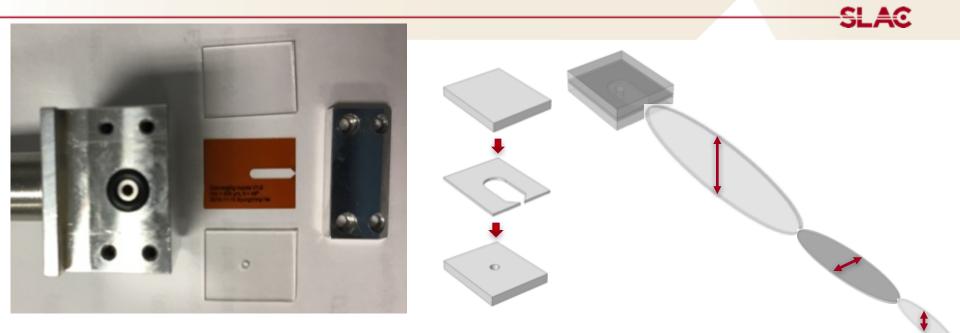
- **Right Place:** In-house nanofabrication facility will produce new scientific advances and support activities at LCLS, SSRL, and SLAC. A semi-shared facility provides much greater flexibility and freedom compared to primarily user facilities at other national labs.
- Right Tools: Nano-prototyping capabilities with direct-write tools efficiently increases scientific productivity and innovation leading to scientific/technological breakthroughs and future funding opportunities for SLAC.
- **Right People:** Builds community and teamwork among SLAC's directorates by integrating nanoscience and nanofabrication expertise across SLAC. In-house nanofabrication expertise allows for accountability and teamwork within SLAC. It also allows for efficient productivity in the unique operational environment of

light sources.



Slide materials courtesy of Anne Sakdinawat

## Single Fluid Nozzle



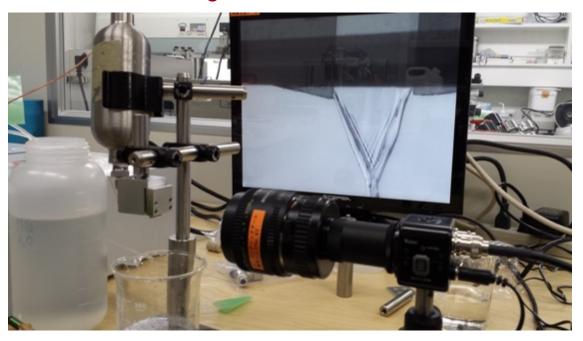
- Microchip: 1mm-thick glass slides + Kapton film
  - > UV laser ablation
  - > 20 30 µm beam diameter
- Grinding and polishing
  - > Grinder w/ sample holder



Slide materials courtesy of Byunghang Ha

## **Single Fluid Nozzle**

### **Straight Channel**



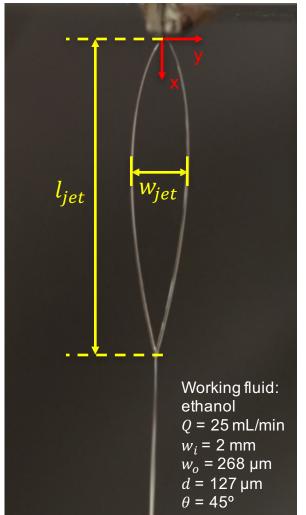
### 13 micron thick by 2mm wide

Slide materials courtesy of Foivos Perakis & Byunghang Ha

### **Converging Channel**

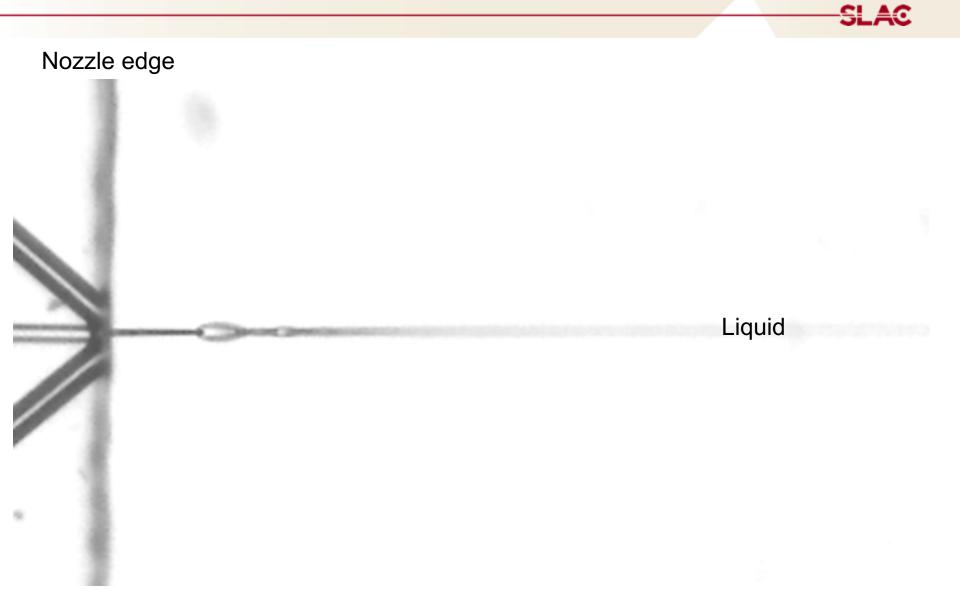
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- There are 2 competing things, inertia (transverse momentum) and surface tension.
- The center of the jet is all about the inertia and the edge is all about surface tension.
- The nozzle geometry completely determines the inertia part and therefore how fast the jet spreads.
- Sheet thickness/nozzle depth at a given length to exit spanwise width ratio is the same for any conditions for a given nozzle geometry.
- The center of the sheet doesn't know the edge exists it spreads out as 1/r.
- The spreading stops at whatever distance the edges collapse back in.
- Higher flow rate means the edges collapse back in farther from the nozzle implying a smaller minimum jet thickness.
- Lower surface tension gives a longer & wider sheet with thinner minimum thickness.

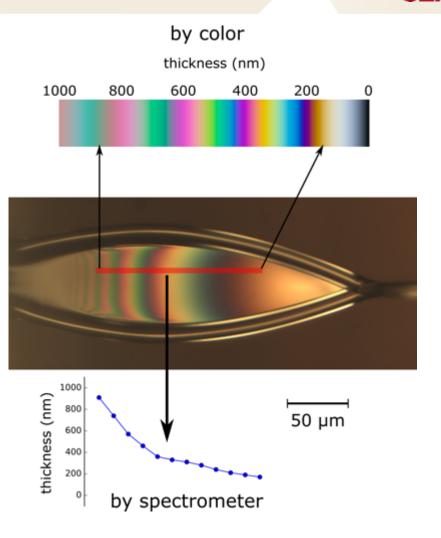
## **2-Fluid Sheet Nozzles**



## **Thin-film interference**

Thickness by color camera and spectrometer agree pretty well.

During FEL experiments, often illuminate with monochromatic laser – also easy to get thickness.



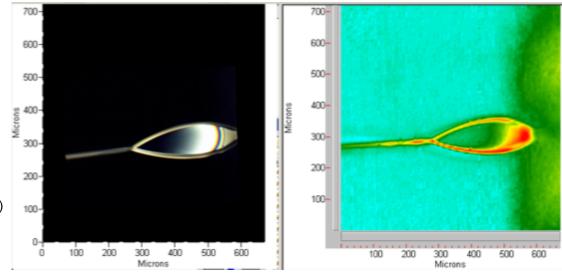
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## **IR transmission spectromicroscopy**

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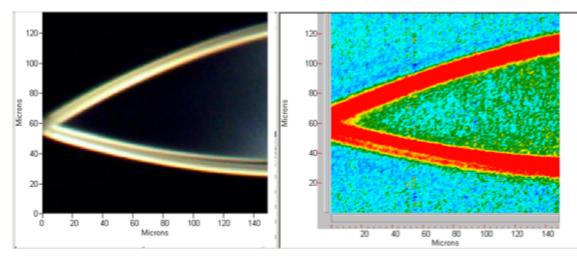


Agilent Cary 620 FTIR microscope 15x objective, NA: 0.6 128 x 128 Pixel detector (16, 384 spectra simultaneously) Low Magz: 720 x 720 μm<sup>2</sup> area with 5.5 μm pixel size High Mag: 140 x 140 μm<sup>2</sup> area with 1.1 μm pixel size



Can adjust sheet thickness to achieve as low as 98% transmission at the O-H stretch mode...

Sheet ~10 nm thick!



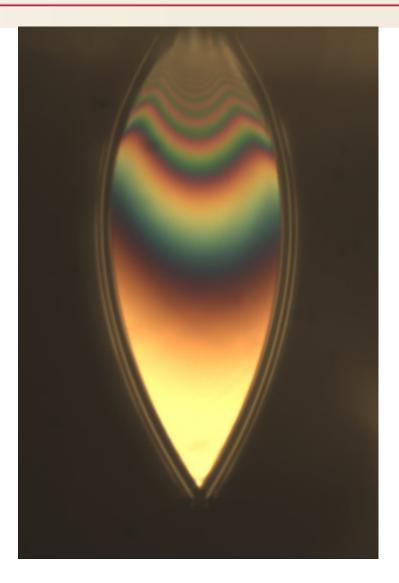
Color scale is transmitted spectral weight of the O-H stretch mode

Slide materials courtesy of Jake Koralek

- ✓ There are 2 competing things, inertia (transverse momentum) and surface tension.
- ✓ The center of the jet is all about the inertia and the edge is all about surface tension.
- x The nozzle geometry completely determines the inertia part and therefore how fast the jet spreads.
- x Sheet thickness/nozzle depth at a given length to exit spanwise width ratio is the same for any conditions for a given nozzle geometry.
- x The center of the sheet doesn't know the edge exists it spreads out as 1/r.
- ✓ The spreading stops at whatever distance the edges collapse back in.
- ? Higher flow rate means the edges collapse back in farther from the nozzle implying a smaller minimum jet thickness.
- Lower surface tension gives a longer & wider sheet with thinner minimum thickness.

## Edge Effects

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## Have them manufactured. Manufacturer sells them to anyone.

## **Status**

### SLAC

### Single-fluid straight nozzle

- Decide on port layout
- Release to Fab

## Single-fluid converging nozzle

- Decide on port layout
- Release to Fab

### 2-fluid nozzle

• Released to Fab (sold by Micronit, interface sold by Neptune fluid flow systems)

## 3-fluid nozzle

Test Prototypes



## Design Guideline for Microfluidic Device and Component Interfaces (2 pubs)

**Editors:** Henne van Heeren (enablingMNT), Tim Atkins (Blacktrace/Dolomite), Nicolas Verplanck and Christine Peponnet (CEA-LETI), Peter Hewkin (CfBI), Marko Blom and Wilfred Beusink (Micronit), Jan-Eite Bullema (TNO), Stefan Dekker (University of Twente).

## With contributions / suggestions and support from persons from the following organisations:

APIX, Axxicon, Bronkhorst, CEA-Leti, CfBI, CMC Microsystems, Corsolution, Cytocentrics, Diagnostics Biosensors, DIBA, Dolomite, enablingMNT, EV Group, EVEON, Fluigent, IMTag, IMTEK, Invenios, IPHT, IVAM, LioniX, Memsmart, Microfluidic ChipShop, Microfluidic Consortium, Micronit, MinacNed, NIST, Philips, PhoeniX, Qmicro, SCHOTT Technical Glass Solutions, Semi, SIMTech Microfluidics Foundry, Skalene, Sony DADC, Stanford University, Stiplastics, TNO, University College London, University Twente, and many others.

#### Comments, suggestions and questions regarding this document can be addressed to:

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Assume hardware has standard interface for standard instrument configurations.

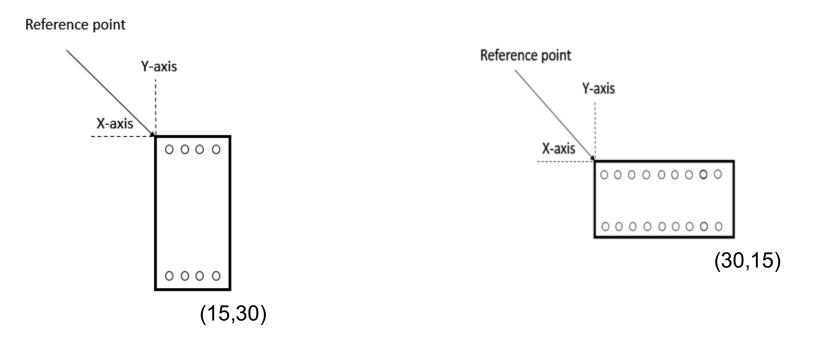
Assume high degree of automation.

In near term assume chip dimensions small in near term

- Microtiter
- "credit card" chip 85.60 × 53.986 mm
- microscope slide (75x25)
- Caliper chip 22.28 mm X 36.88 mm (12.4,9) spacing
- None of the above

Assume we need half angle XXX(45?) for the scattered beam.

## **Standardization (naming)**

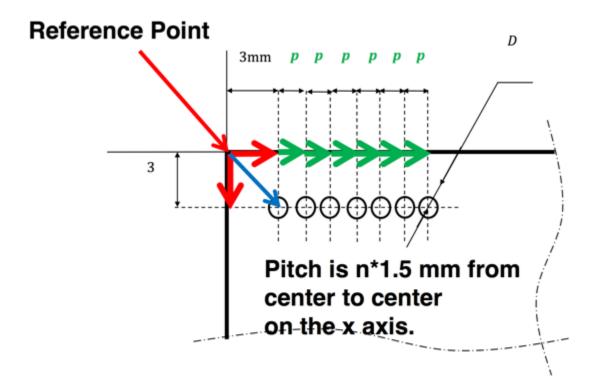


### 15\*30 mm chip with axes and reference point. 30\*15 mm chip with axes and reference point.

From white paper "As a preference one should chose the naming (and with that the X axis) in such a way that (most of) the microfluidic connections are on the side of the X axis." What about for injectors?

From Design Guideline for Microfluidic Device and Component Interfaces

port pitch, i.e. the distance between the centres of two ports are to be based on a 1.5mm grid (or 0.75?)



### Center of first hole is at (3 mm, 3 mm) from reference point

From Design Guideline for Microfluidic Device and Component Interfaces

-SLAC

Outline 17mm x 6mm Ports (3,3) (6,3) (9,3) Thickness 0.8mm

